

Electronic Patent Application Fee Transmittal

Application Number:	10586788
Filing Date:	02-Sep-2008
Title of Invention:	PLASMA EXCITED CHEMICAL VAPOR DEPOSITION METHOD SILICON/ OXYGEN/NITROGEN-CONTAINING-MATERIAL AND LAYERED ASSEMBLY
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Attorney Docket Number:	INF 2006 VJ 33543 US

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U.S. National Stage under 35 USC 371 Filing Fees

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Utility Appl issue fee	1501	1	1510	1510
Publ. Fee- early, voluntary, or normal	1504	1	300	300

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
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Total in USD (\$)				1810